



520.43429X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Minoru YOSHIDA et al.
Serial No.: 10/765,920
Filed: January 29, 2004
Title: PATTERN DEFECT INSPECTION METHOD AND ITS APPARATUS
Group: 2878
Examiner: ZETTL, Mary E.
Confirmation No.: 2671

AMENDMENT

Mail Stop: AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

February 13, 2006

Sir:

In response to the Office Action dated October 13, 2005, please amend the above-identified application as listed below and as set forth on the following pages:

Amendments to the claims begin on page 2;

Remarks are included beginning on page 13; and

Authorization is included on page 19.